



FECR Ion Source Development and Challenges

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ECRIS'20, Sept. 28~30, 2020, Virtual Conference, hosted by MSU



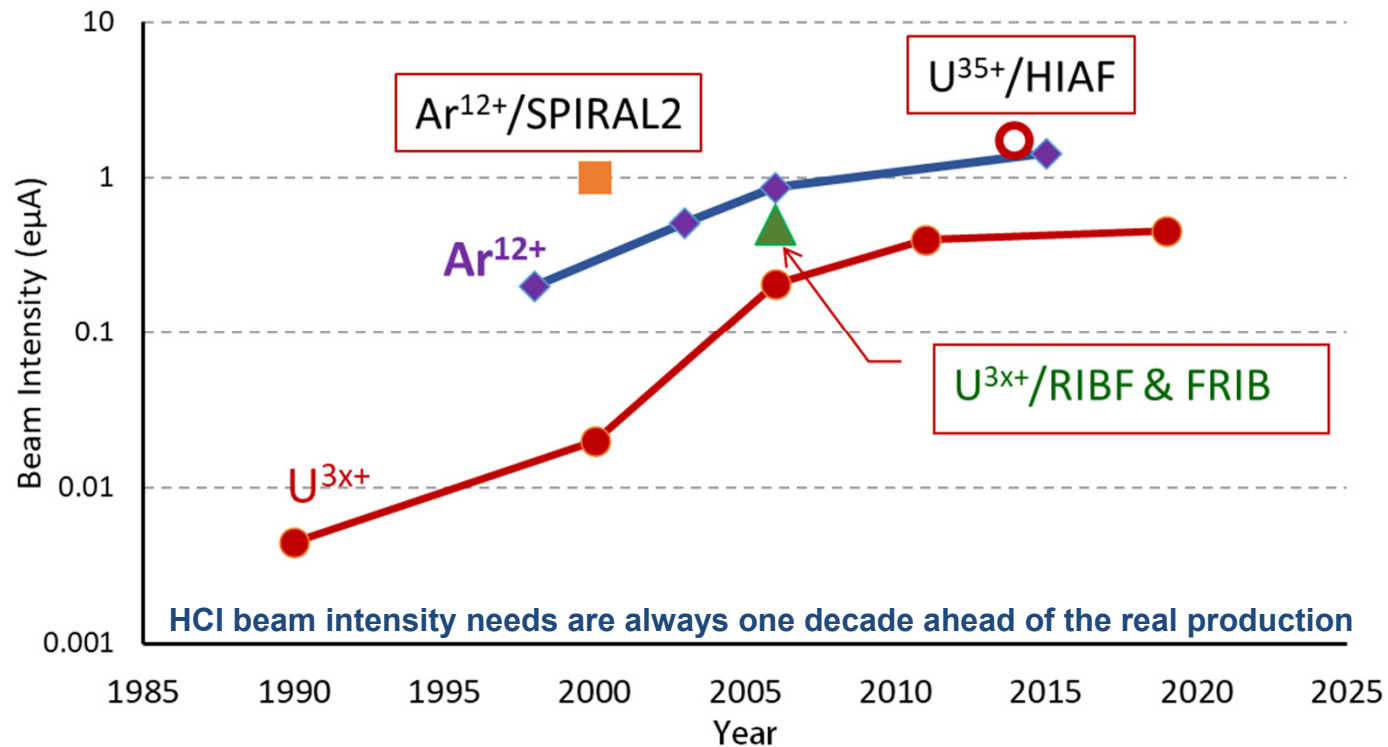
Outline

- Intense HCI Beam Needs
- Status of Intense HCI Beam Production
- Perspectives of Next Generation ECRIS
- Status of FOCR Development
 - ◆ 45 GHz Nb₃Sn Magnet Development
 - ◆ Conventional Ion Source Physics & Technologies
- Summary



Intense HCI Beam Needs by Accelerators

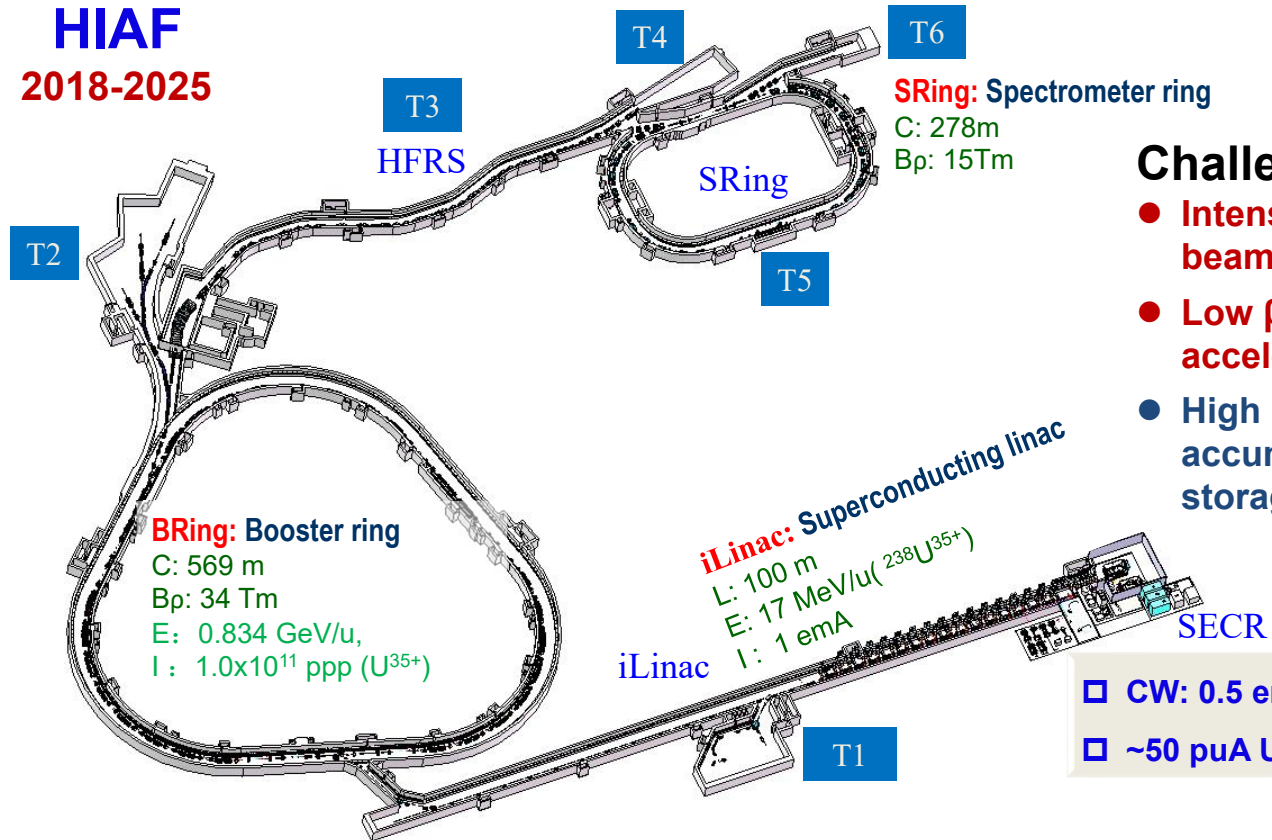
Ar^{12+} and U^{3x+} beam intensities evolution over years





Intense HCI Beam Needs of HIAF

HIAF
2018-2025



Challenges

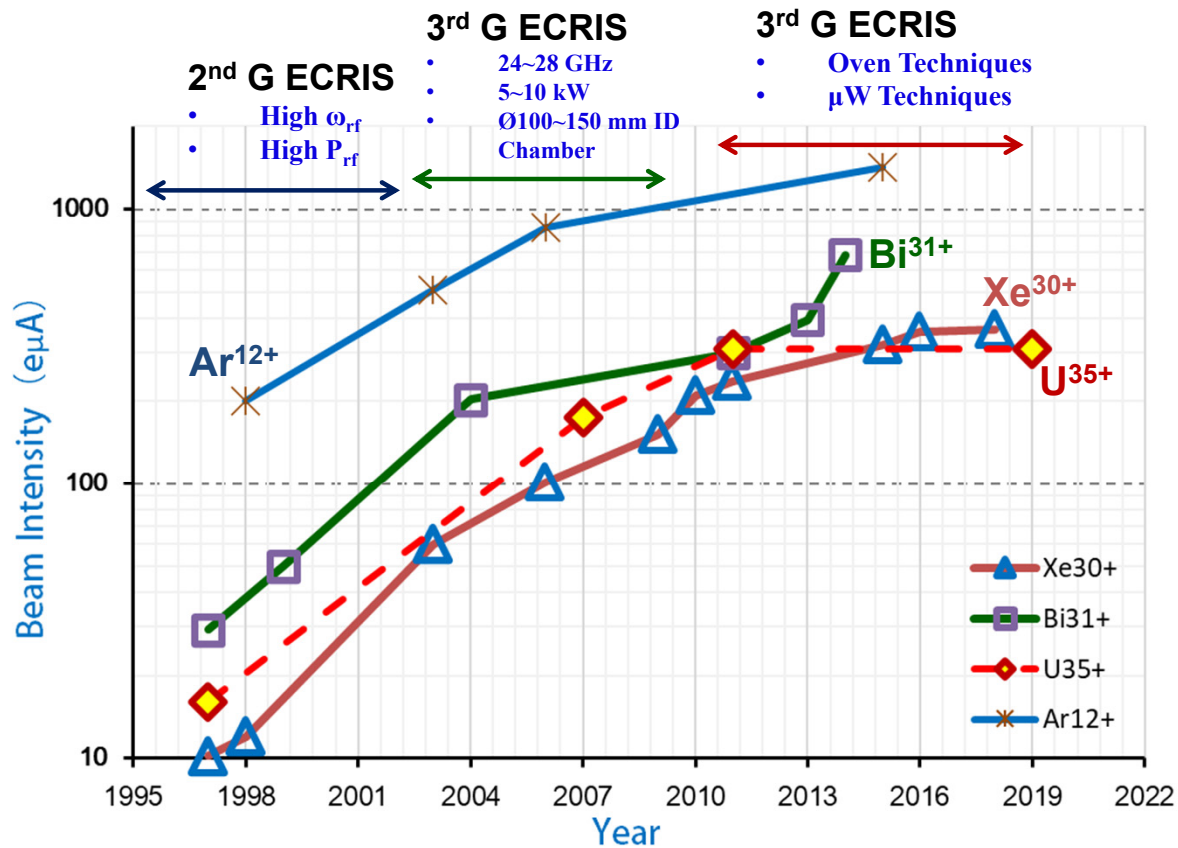
- Intense highly charged heavy ion beams production
- Low β intense heavy ion beam acceleration
- High intensity heavy ion beam accumulation, acceleration in storage ring

□ CW: 0.5 emA U^{46+}

□ ~ 50 puA $U^{35+}/\leq 5$ Hz@0.2~2 ms



Status of Intense HCI Beam Production



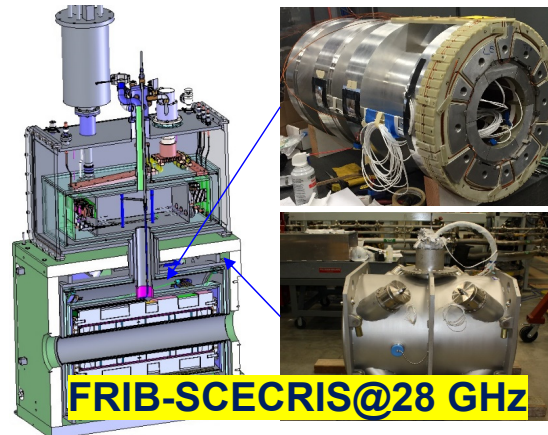


Status of Intense HCl Beam Production



Typical 3rd G. ECRISs for intense U^{3x+} beams

- U^{3x+}: 10~15 μ A
- 1/4~1/5 of HIAF needs



4th G. ECRIS

- U^{3x+}: 30~50 μ A
- U^{4x+}: 5~10 μ A

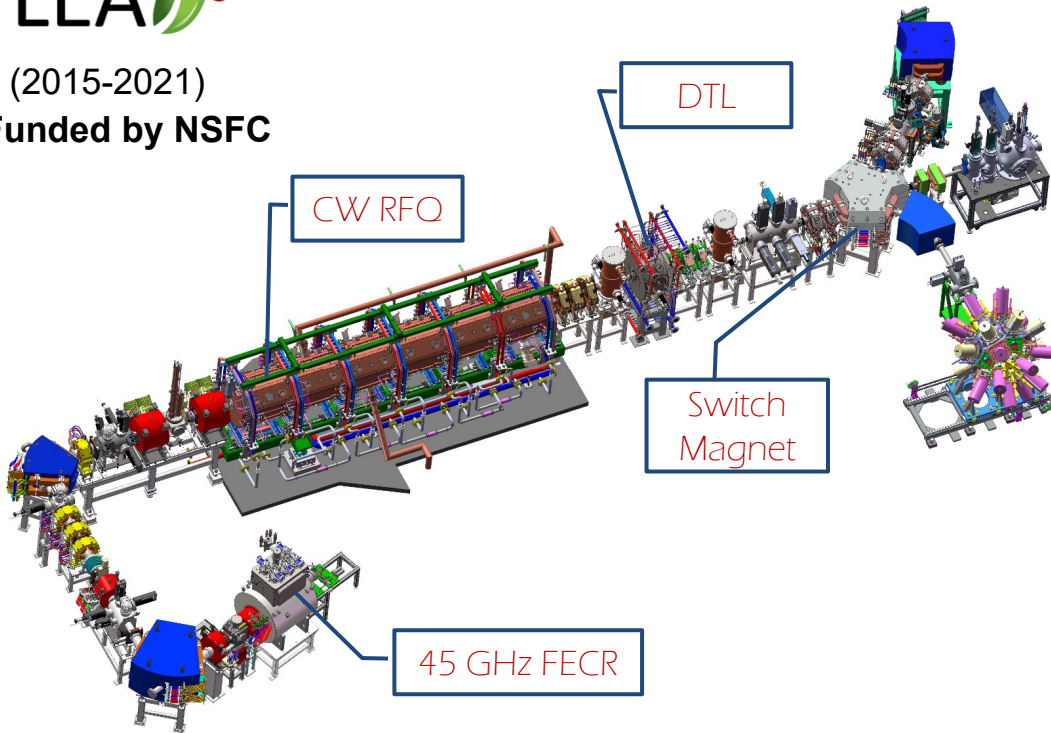


Perspectives of Next Generation ECRIS

LEA

(2015-2021)

Funded by NSFC



Significance:

Ultimate conditions for physics with low energy HCI beams:

- Material irradiation research
- Highly charged atomic physics
- Low energy nuclear physics

Prototyping for HIAF:

- 45 GHz ECR Ion Source
- 81.25 MHz CW 4-vane RFQ
- Intense heavy ion beam production, transmission and acceleration

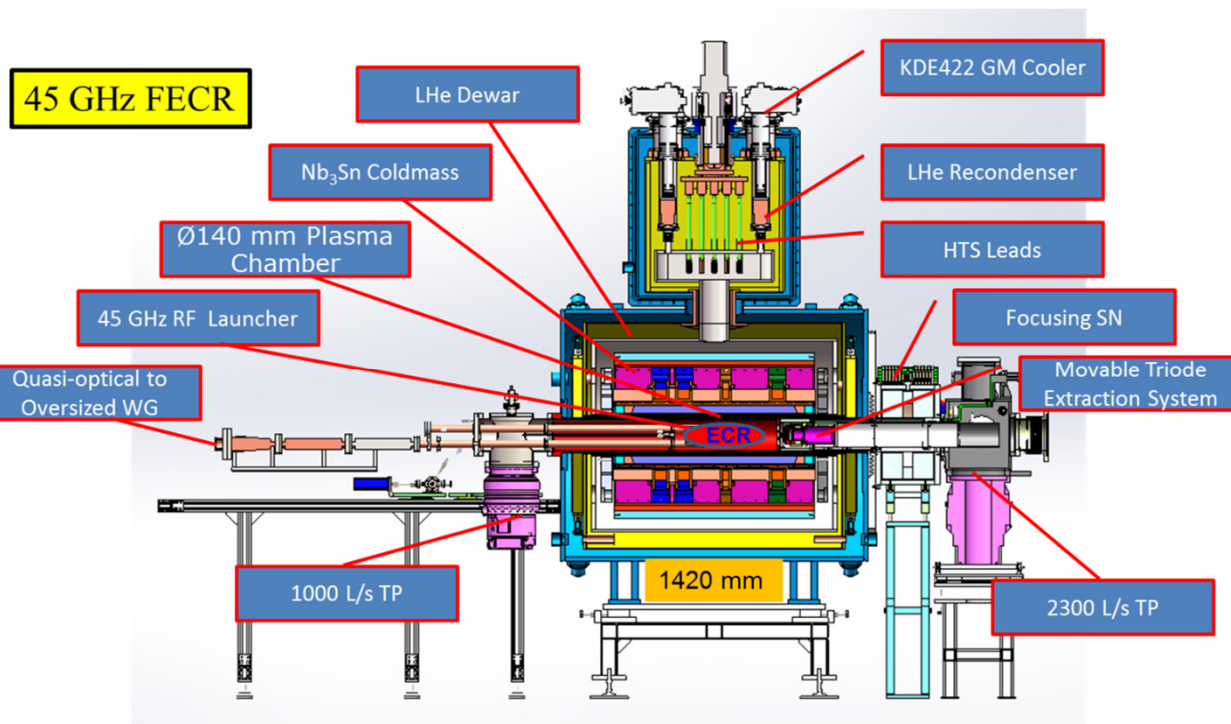


Perspectives of Next Generation ECRIS

FECR (First 4th generation ECR ion source)

Specs. of FECR

Specs.	Unit	Value
Frequency	GHz	45
RF Power	kW	20
Chamber ID	mm	$\geq \varnothing 140$
Mirror Fields	T	$\geq 6.4/3.2$
B_{rad}	T	≥ 3.2
Mirror Length	mm	~ 500
B_{max} in conductor	T	~ 11.8
Magnet coils	/	Nb ₃ Sn
Nb ₃ Sn		$J_c > 1500 \text{ A/mm}^2 @ 12\text{T}$
Cooling Capacity@4.2 K	W	> 10.0

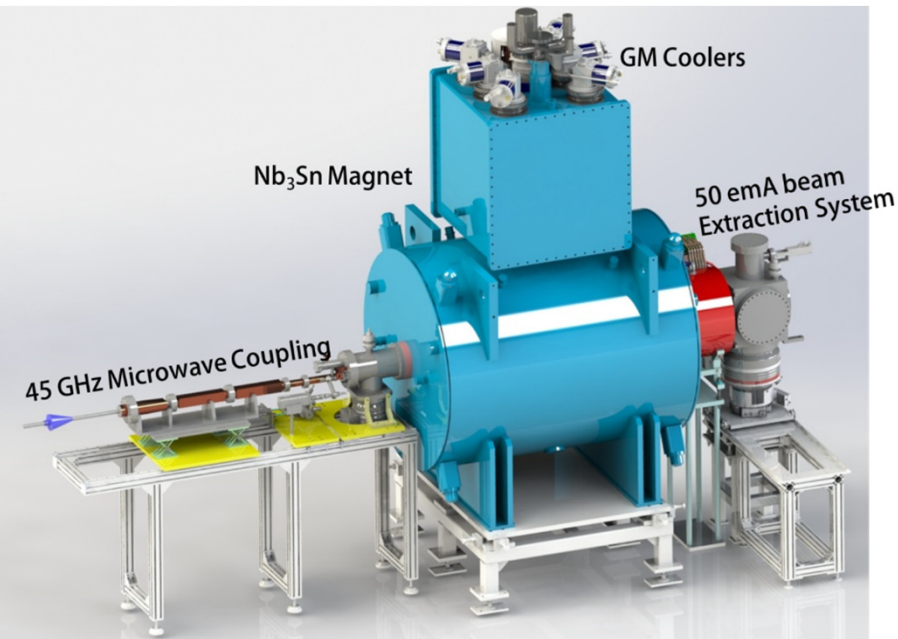


H. W. Zhao et al., Review of Scientific Instruments **89**, 052301 (2018)



Perspectives of Next Generation ECRIS: Challenges

FECR (First 4th Generation ECR ion source)



- ◆ Reliable SC-magnet for 45 GHz plasma confinement
- ◆ Effective coupling to the plasma of 20 kW/45 GHz microwave power
- ◆ 20 kW microwave heated plasma operation reliability and stability: Plasma chamber and dynamic stability
- ◆ Strong bremsstrahlung radiation problems
 - Heat sink in cryostat
 - HV insulator degradation
 - Risk of coil epoxy degradation
- ◆ Intense high charge state ion beam (20-40 emA) extraction, transport and beam quality control
- ◆ Intense metallic beam production, especially of refractory materials: U, W, Ta, Mo, Ti, Ni...

Liangting Sun, ICFA-Newsletter 73, p34.



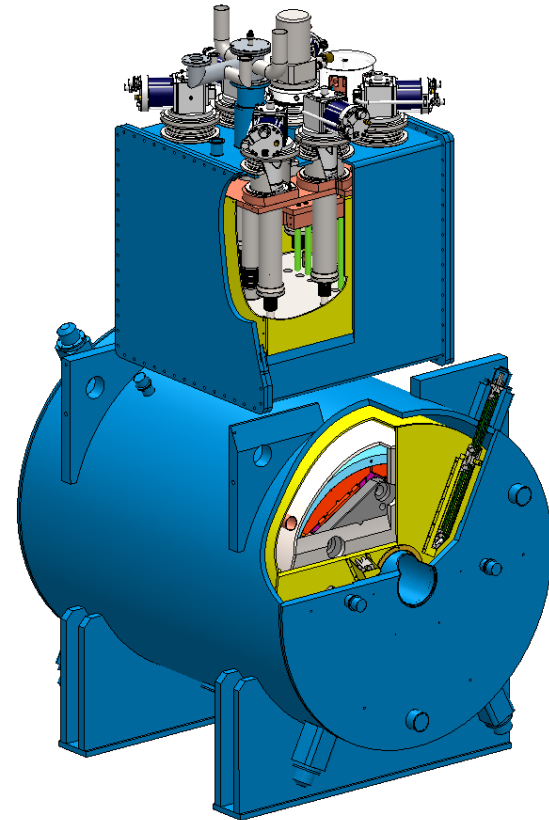
Status of **F**ECR Development: **Magnet**

Cold mass

- ◆ High quality reliable Nb₃Sn sextupole coil production
- ◆ Precise and efficient pretension and clamping structure
- ◆ Fast quench detection and active protection

Cryostat

- ◆ Safe suspension system for operation and transport of 3.5 tons cold mass
- ◆ Precise installation and alignment of cold mass
- ◆ High voltage safe instrumentation
- ◆ Sufficient dynamic cooling power @4.2 K

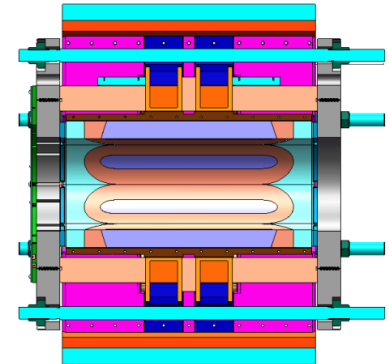
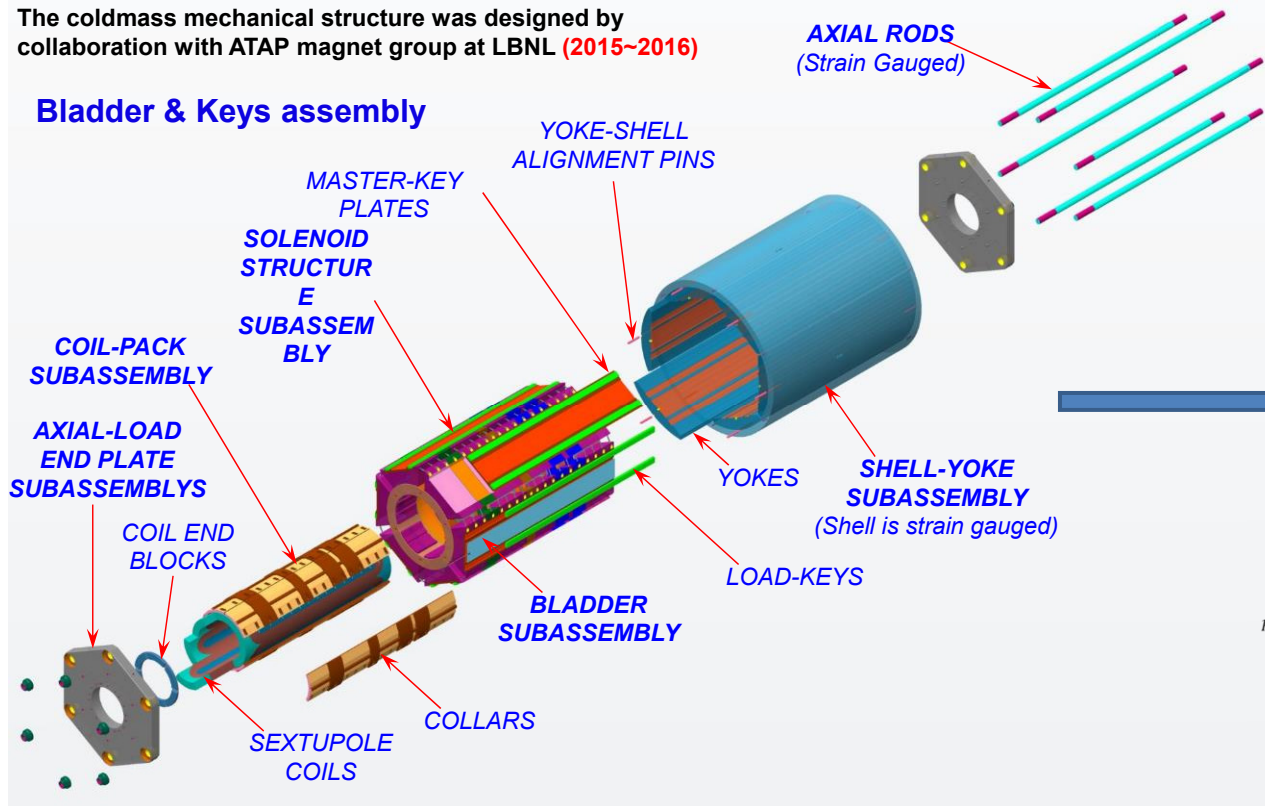




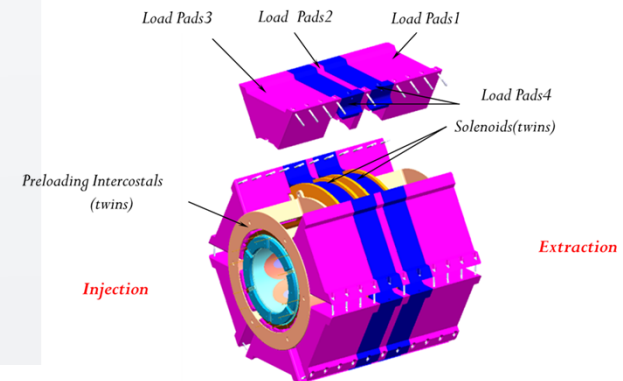
Status of F ECR Development : Nb_3Sn magnet

The coldmass mechanical structure was designed by collaboration with ATAP magnet group at LBNL (2015~2016)

Bladder & Keys assembly



1/2 length prototype



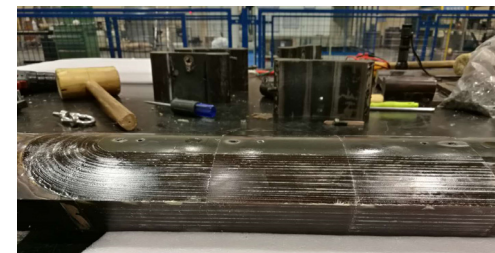
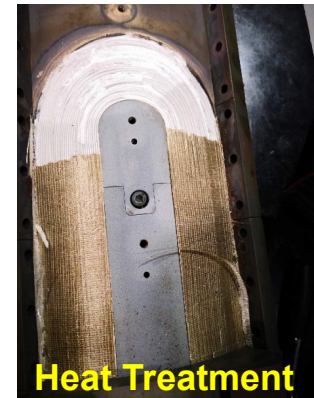
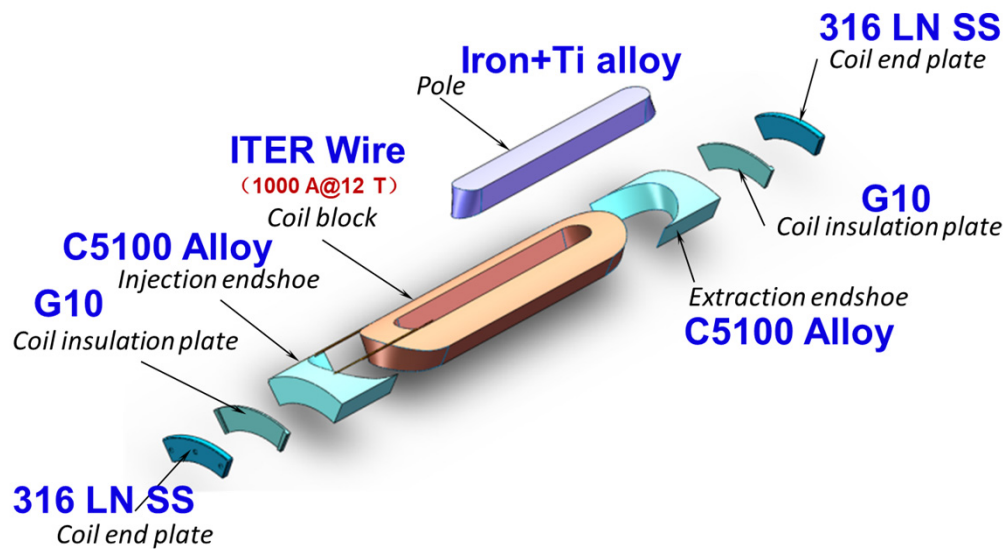
R&D: 2017~now

M. Juchno, et al., IEEE Trans. Appl. Supercond., vol. 28, no. 3, Apr. 2018, Art. no. 4602806

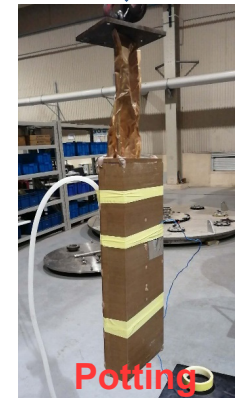




Status of **F**ECR Development : **Nb₃Sn** Coil

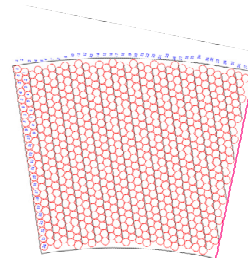
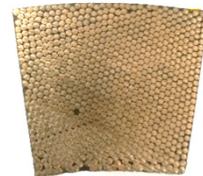
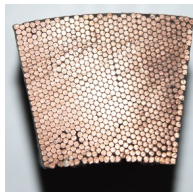
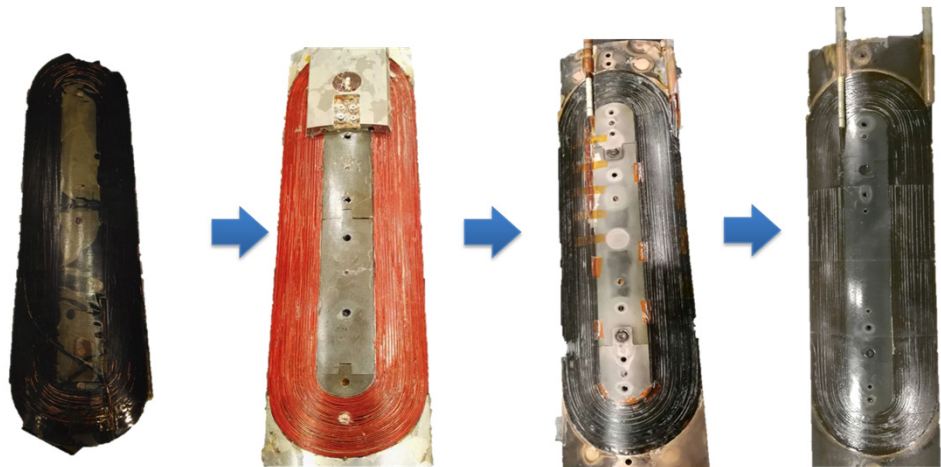


- Mechanical mapping
- Detailed Q/A





Status of **F**ECR Development : **Nb₃Sn** Coil



2016.12

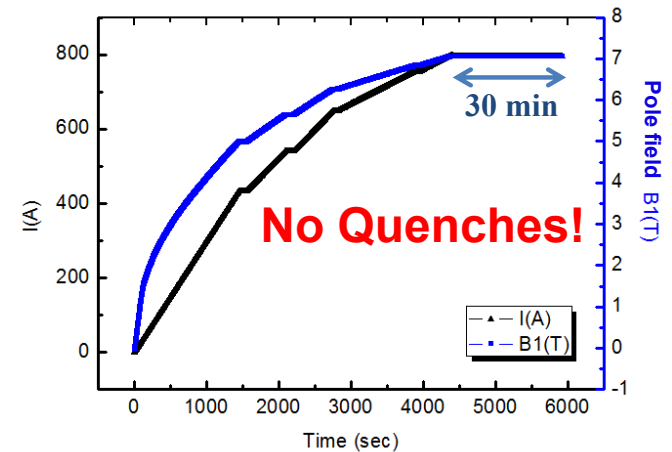
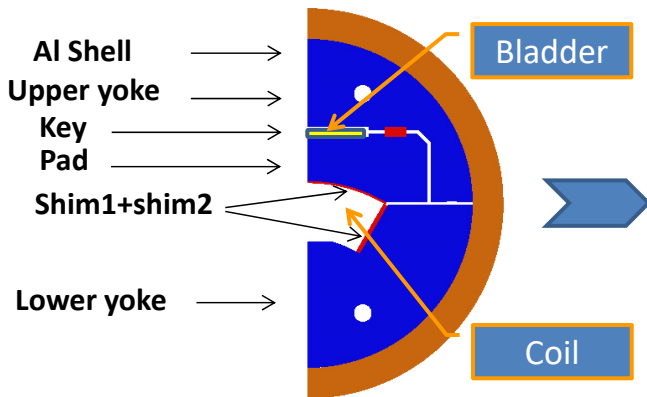
Journey of coil R&D

2018.12

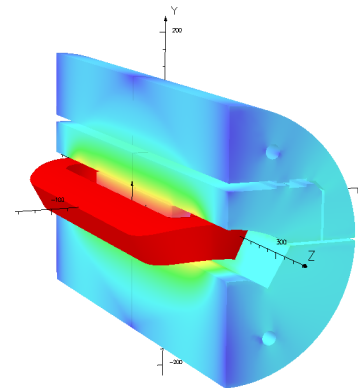
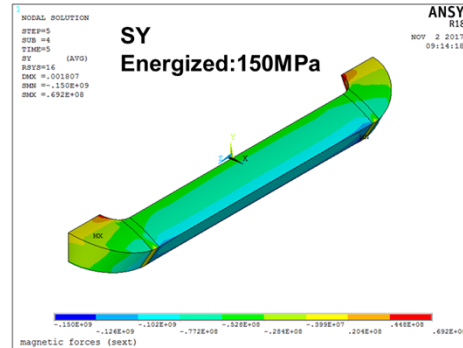
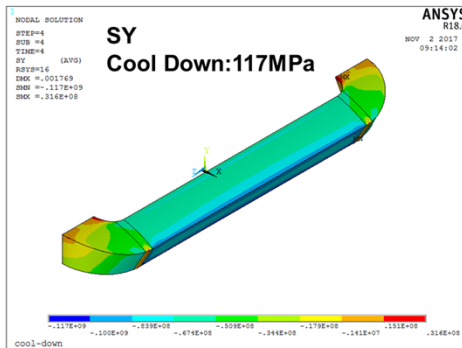




Status of **F**ECR Development : **Nb₃Sn** Coil



A Mirror Structure for sextupole cold test

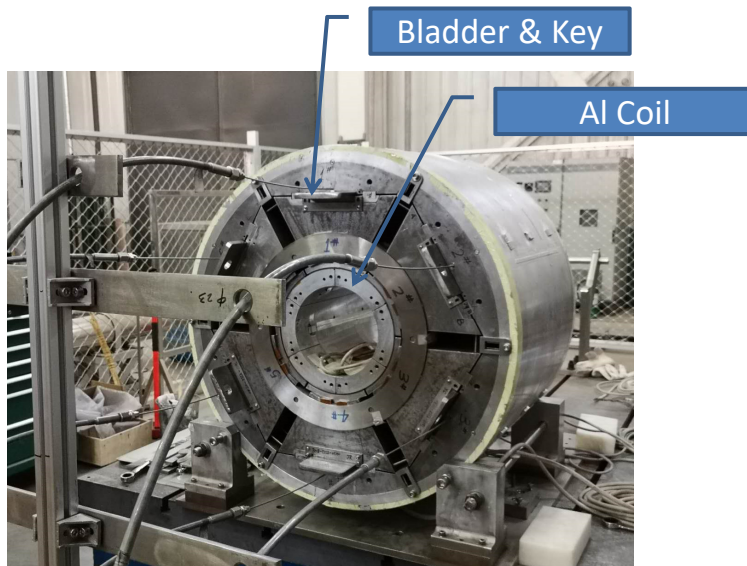


- Highest field in superconductor: **10.4 T**
- LF : **80%** of short sample

Yuquan Chen, et al., IEEE Trans. Appl. Supercond., vol. 31, no. 1, Jan. 2021, Art. no. 4100105

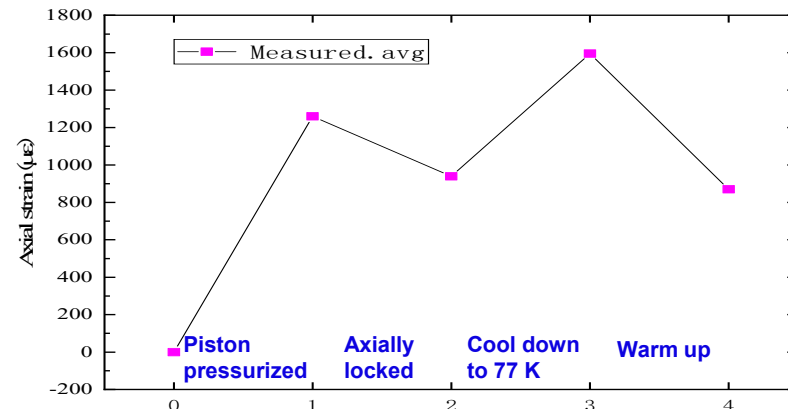
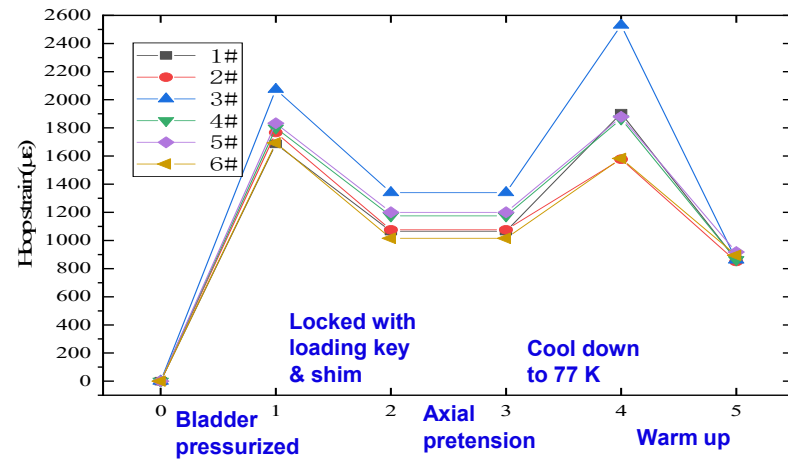


Status of F ECR Development : structure



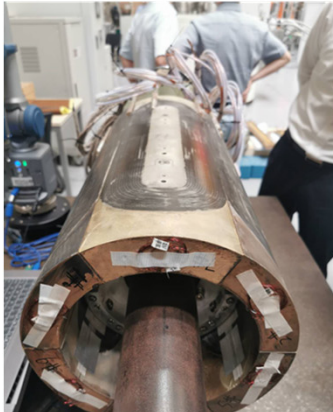
1/2 prototype with Al dummy coil mockup

Whole process Strain- Guaged

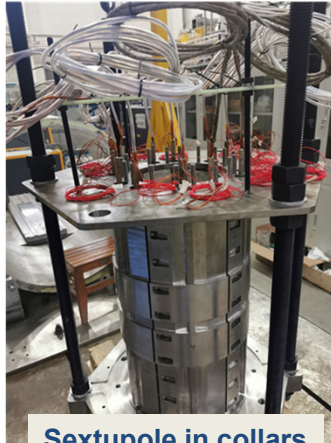




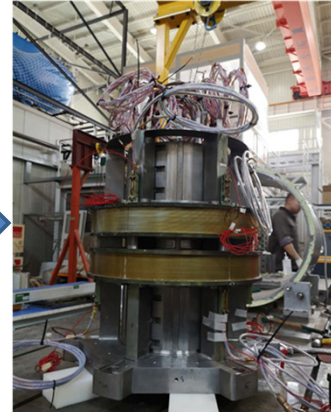
Status of **F**ECR Development : $\frac{1}{2}$ coldmass



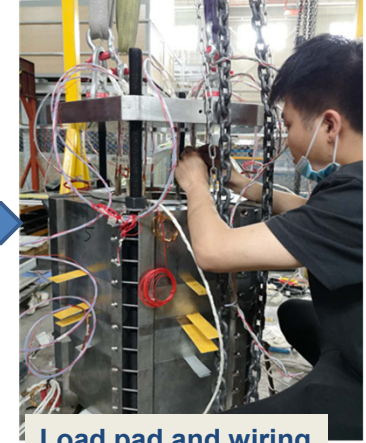
Sextupole pre-assembly



Sextupole in collars



Sextupole & solenoids



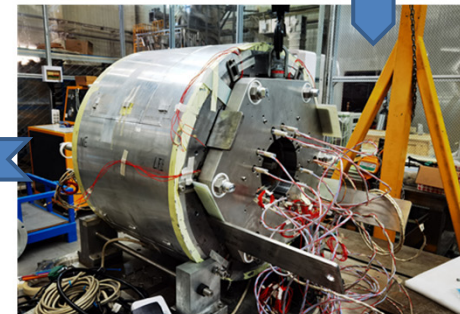
Load pad and wiring



Instrumentation in Pizzabox



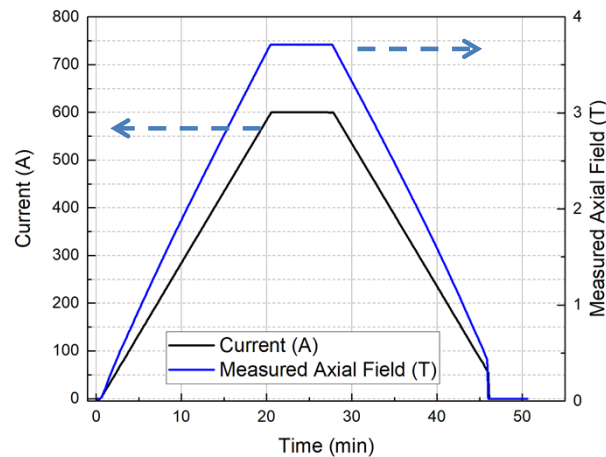
Axial preload with pistons



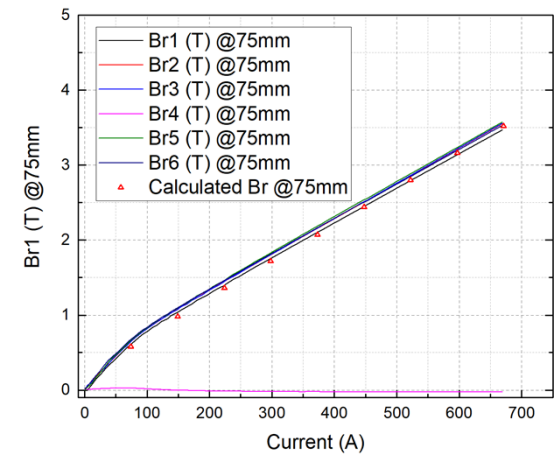
Radial preload with bladder & keys



Status of **F**ECR Development : **Cold Test**



- Solenoid only energized to 100% design current 600 A
- No quenches!
- Field consistent with calculated

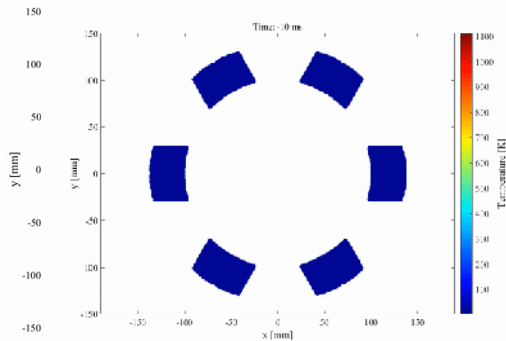


- Sextupole only energized to 90% design current= 671 A (power supply malfunction)
- No quenches!
- Field consistent with calculated

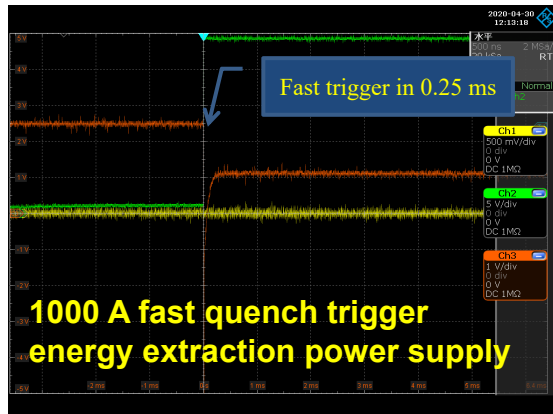


Status of **F**ECR Development : **Q**uench protection

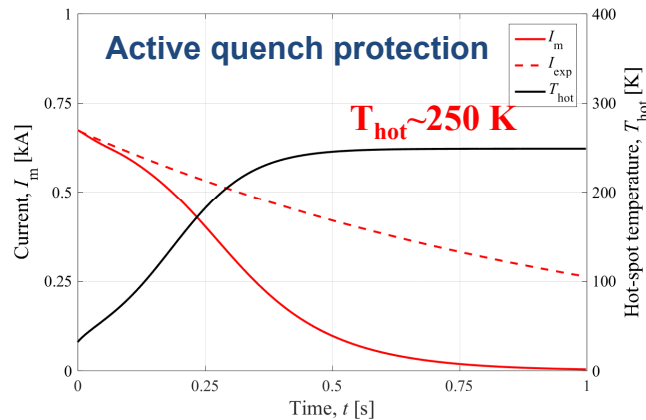
Sextupole passive quench protection



E. Ravaoli, et al., IEEE Trans. Appl. Supercond., vol. 28, no. 3, April 2018, Art. no. 4700906

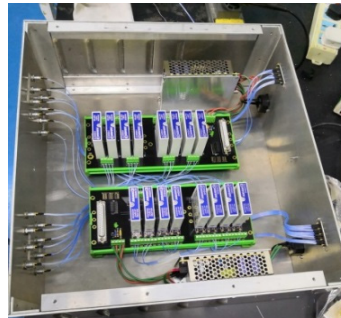


**1000 A fast quench trigger
energy extraction power supply**

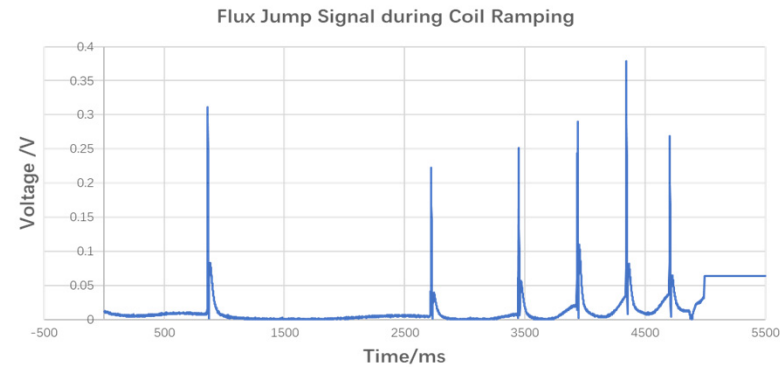


$$\begin{aligned} I_0 &= 673 \text{ A} \\ R_{EE} &= 2.4 \text{ } \Omega \\ U_{EE} &= 1650 \text{ V} \end{aligned}$$

Fast quench detection,
validation and triggering
energy extraction in:
17 ms



Fast quench detection (~ 20 mV,
10 ms) system based on FPGA



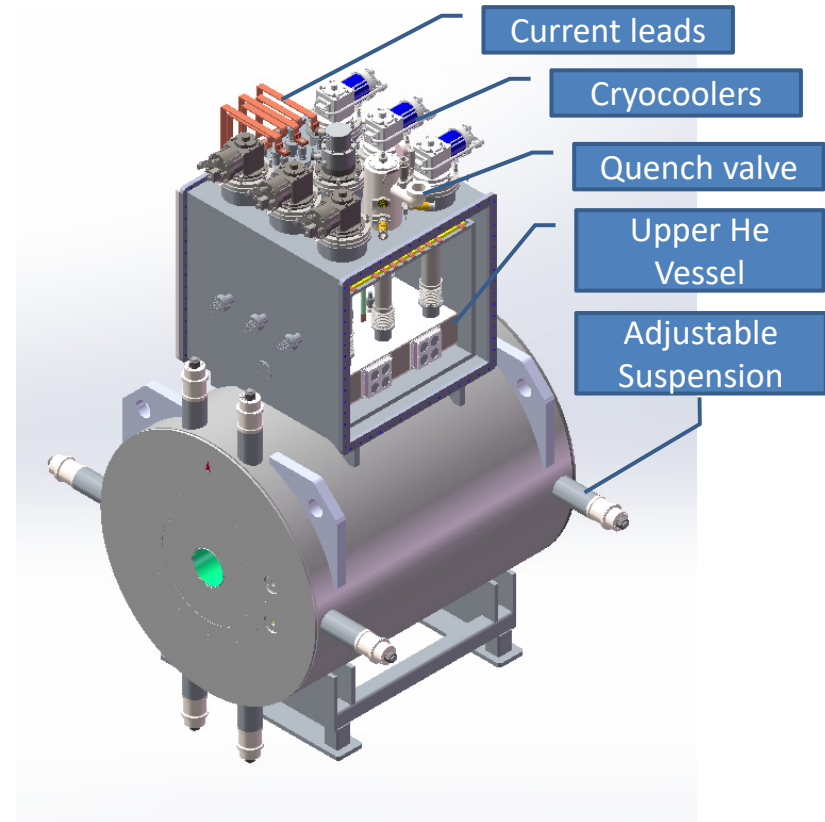
Flux jump adds additional difficulty to quench
protection and coil safety



Status of **F**ECR Development : **Cryogenic system**

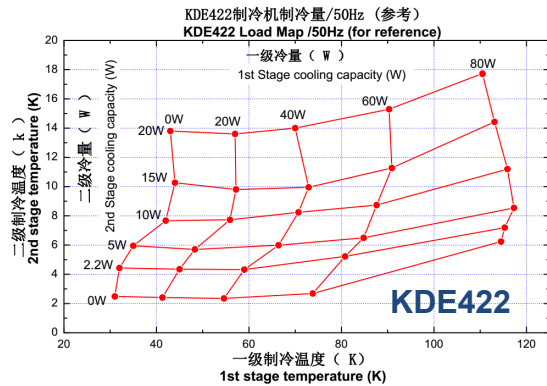
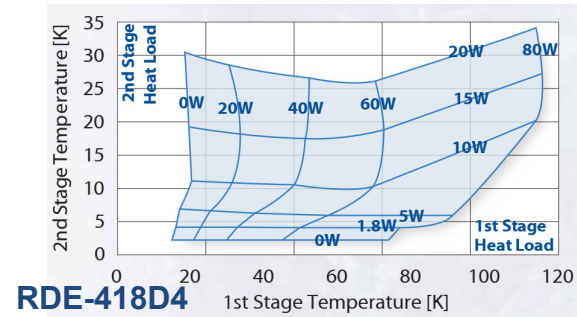
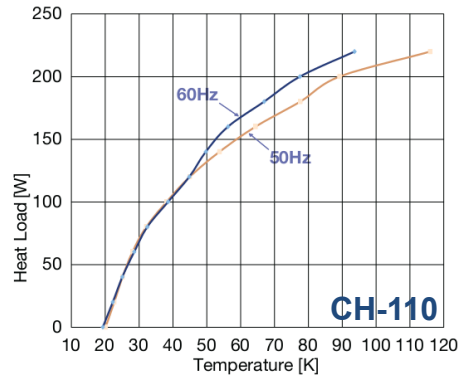
Key parameters of FOCR cryostat

Parameters	Value	Note
Operation Temp. (K)	4.3 K	
Magnet Cooling	LHe bathing and "0" boiling-off	
Stored Energy (MJ)	~1.6	100% currents
Required heat load (W)	≥ 12	~2 W static at 100% currents
Warm Bore (mm)	$\varnothing 162$	
LHe Volume (L)	~330	
Cryocoolers	6 two-stage + 1 single stage coolers	Cold service enabled
Dimension (mm)	L1456 $\times$ $\varnothing$ 1200 $\times$ H2690	
Total weight (ton)	~6.1	





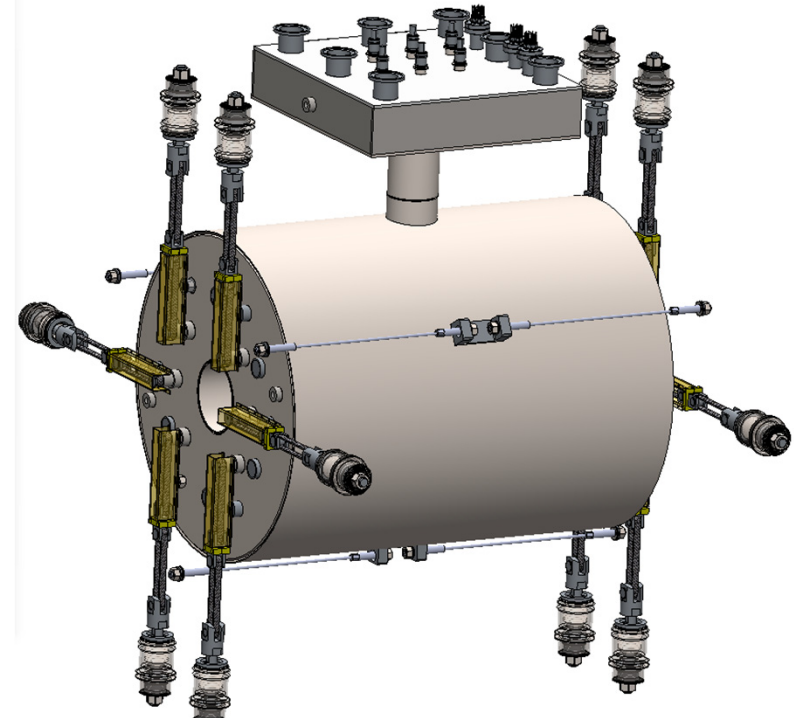
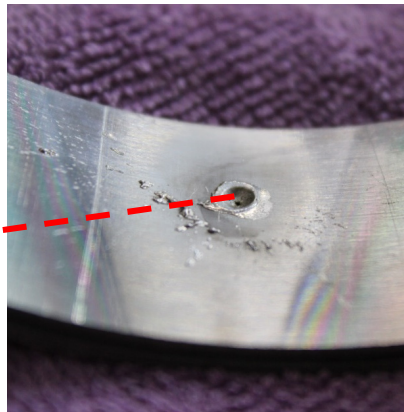
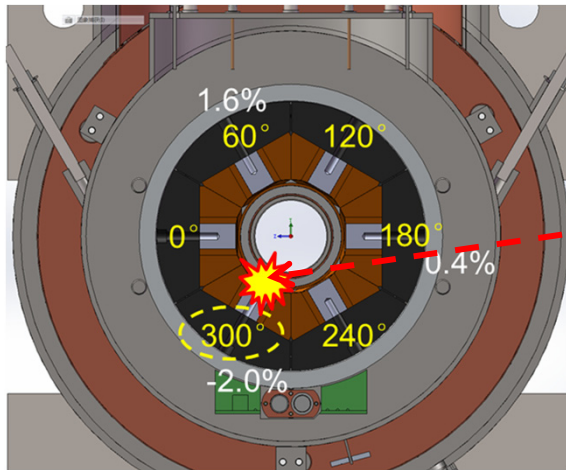
Status of **F**ECR Development : **Cryogenic system**



Model	1 st Stage	2 nd Stage
CH-110	130 W@50 K	N/A
KDE422	~20 W@50 K	≥2.2 W@4.2 K
RDE-418D4	~42 W@50 K	≥1.8 W@4.2 K
Total	~316 W@50 K	≥12 W@4.2 K



Status of **F**ECR Development : **Cryogenic system**



- Localized heat sink strongly related to field homogeneity
- Field homogeneity:
 - $<1\% \rightarrow$ concentricity $\Delta r < 0.4$ mm
 - $<0.5\% \rightarrow$ concentricity $\Delta r < 0.2$ mm



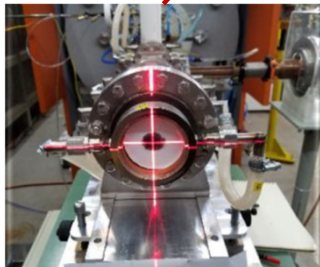
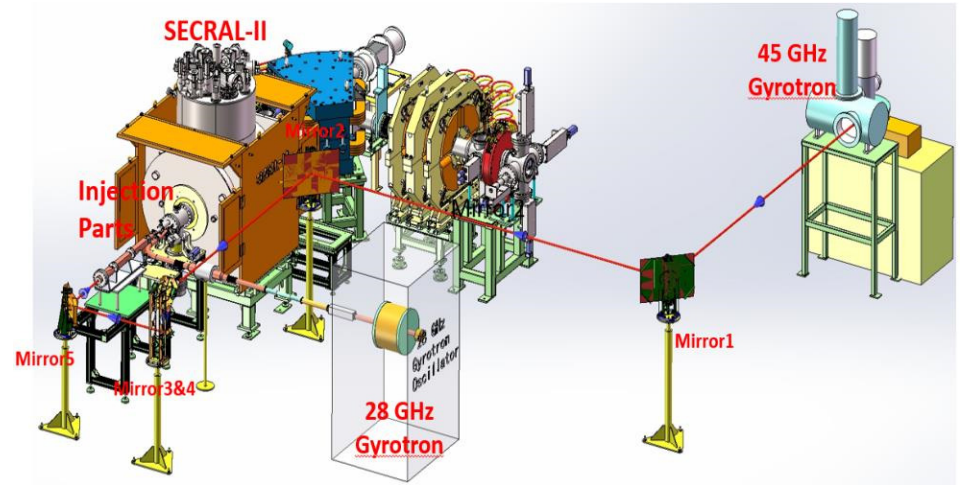
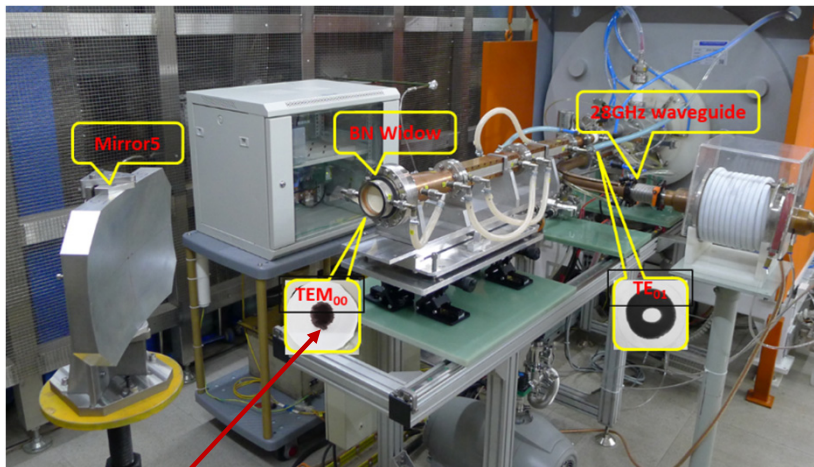
Status of **F**ECR Development : **Conventional Parts**

Parameters	3 rd G. ECRIS	45 GHz FECR	Increased by
Microwave Power (kW)	~10	>20	>2
Ts (keV)	50~60	80~100	>1.5
Microwave Length (mm)	~10	~6	/
Max. Plasma Density (cm ⁻³)	~1X10 ¹³	~2.6X10 ¹³	>2.6
Total Beam Available (mA)	10~20	26~52	>2.6



Status of **F**ECR Development : μ W coupling

45 GHz Microwave System for FOCR

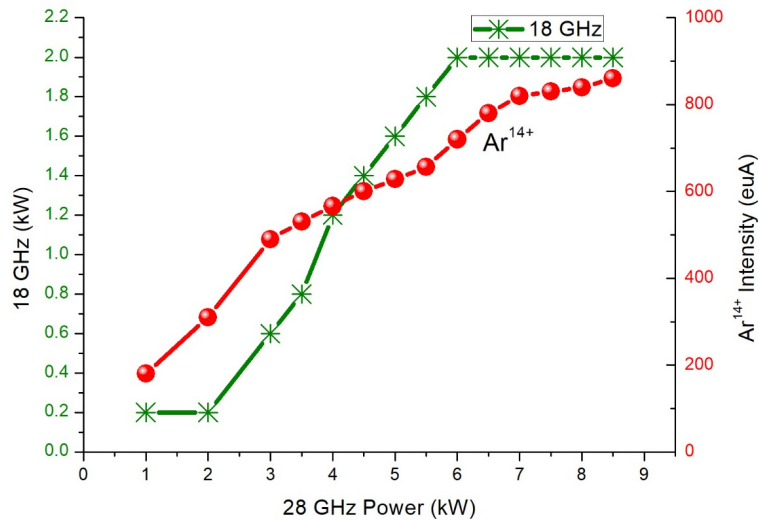


- 45 GHz/20 kW microwave transmission system based on Quasi-optical design
- First 45 GHz ECR plasma with SECRAL-II ion source
- Efficient transmission and coupling demonstrated

J. W. Guo, et al., AIP Conference Proceedings **2011**, 090001 (2018)

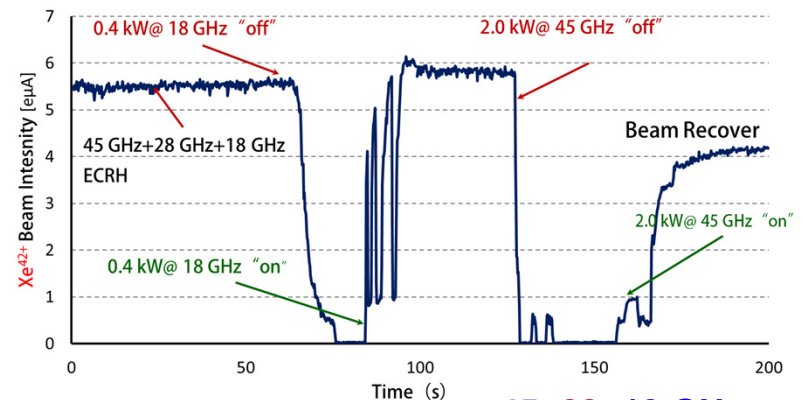
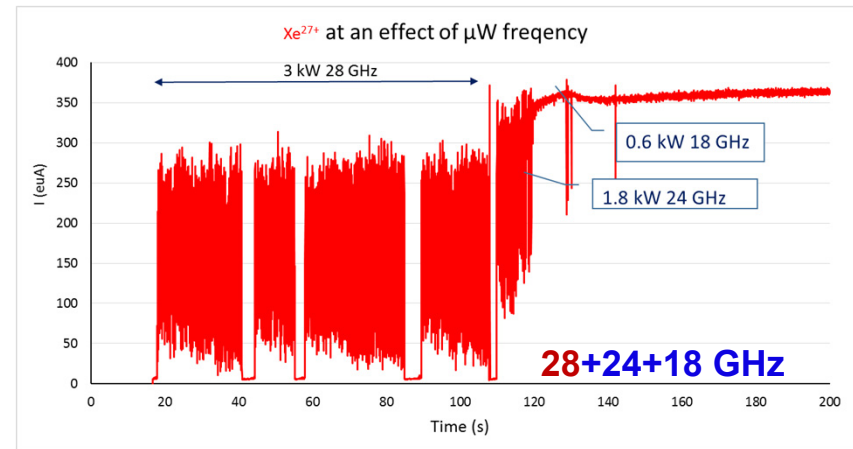


Status of F ECR Development : μW coupling



About multi-frequency ECRH

- Secondary or multi-frequency ECRH is essential
- Optimum frequencies to suppress kinetic instabilities?
- Needed power? (4~5 kW)

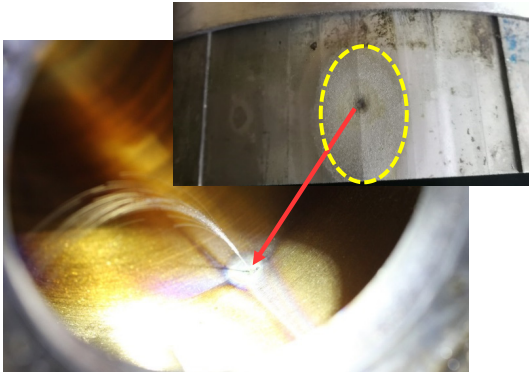


L. Sun, TUA5, ECRIS2018

45+28+18 GHz



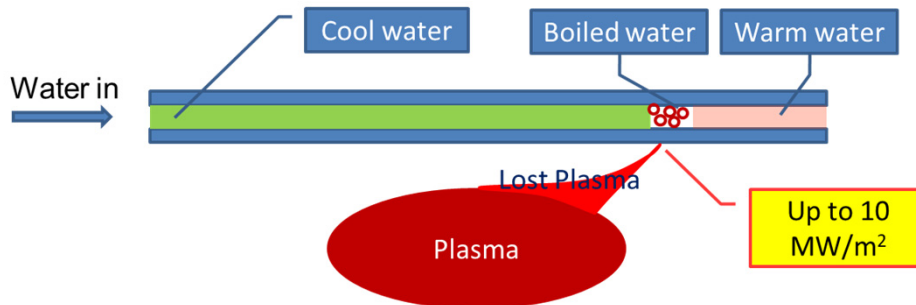
Status of F ECR Development : Plasma Chamber



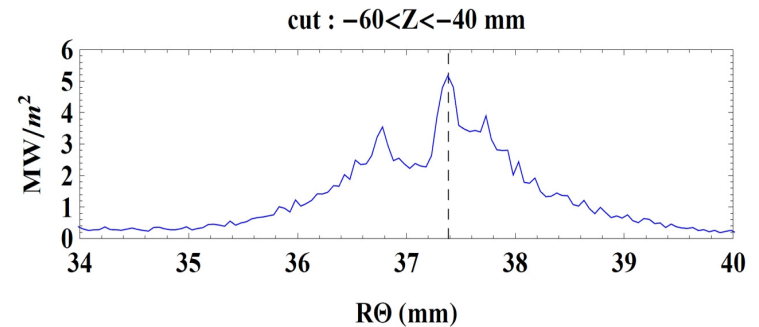
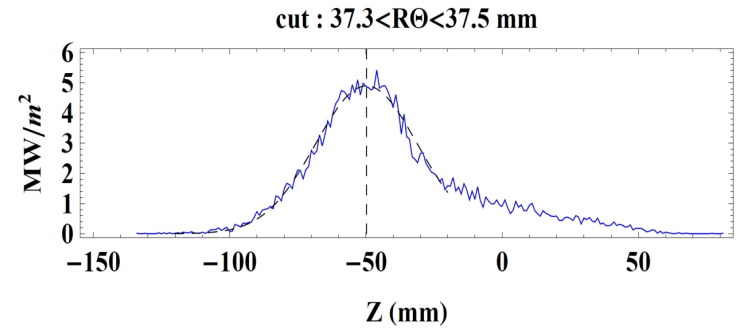
Chamber burnt with SECAL-II
Typically: >7 kW



Chamber burnt with VENUS



LCW pressure of 6 kg/cm², water BP =150~160°C



1 kW μ W~1.25 MW/m² heat sink

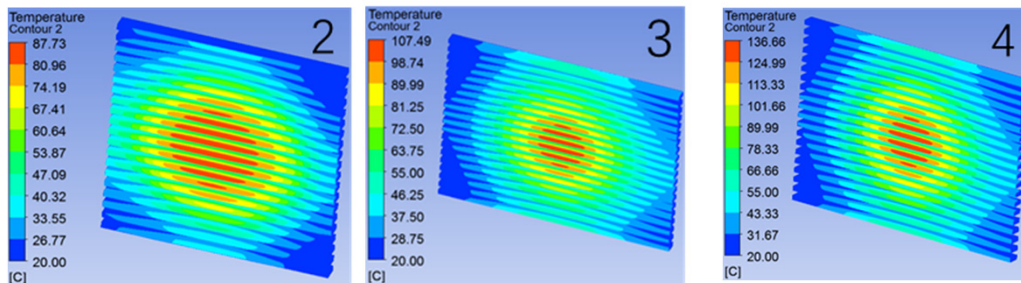
T. Thuillier et al., Review of Scientific Instruments
87, 02A736 (2016)



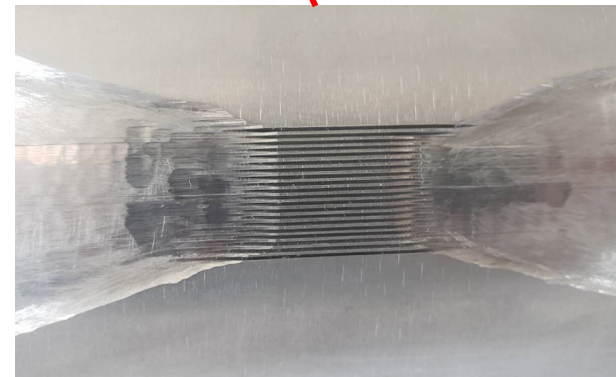
Status of **F**ECR Development : **Plasma Chamber**

	P_{rf} (kW)	T_{max} on Al wall	T_{max} of water at the hottest point
1	10 : averagely distributed	174°C	88°C
2	10 : Gaussian distributed	159°C	78°C
3	15 : Gaussian distributed	229°C	107°C
4	20 : Gaussian distributed	299°C	137°C

Water flow rate: 7 L/min with micro-channel



Water temperature distribution at the chamber wall of weakest plasma confinement point

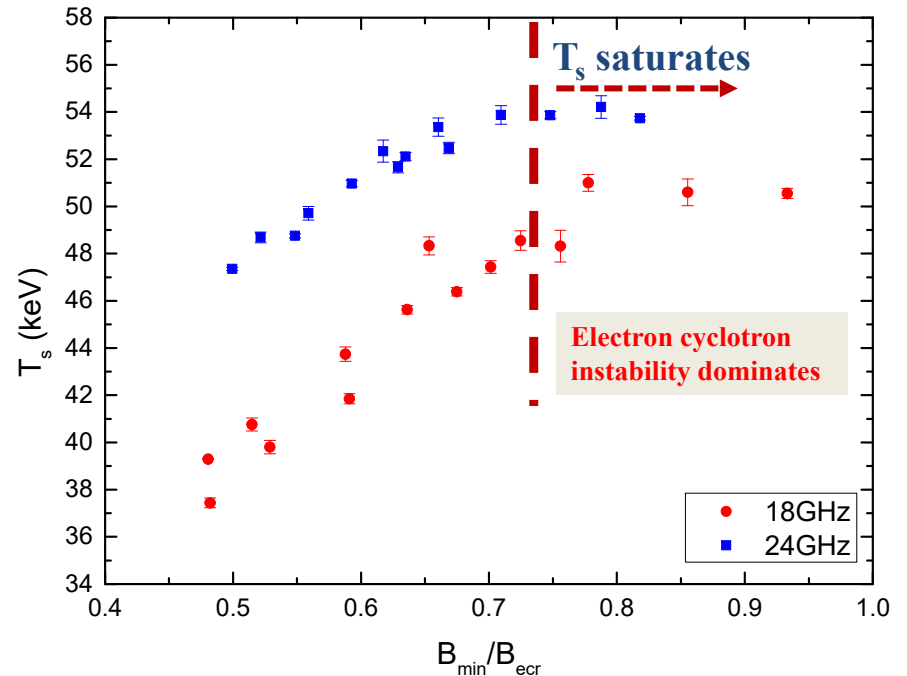
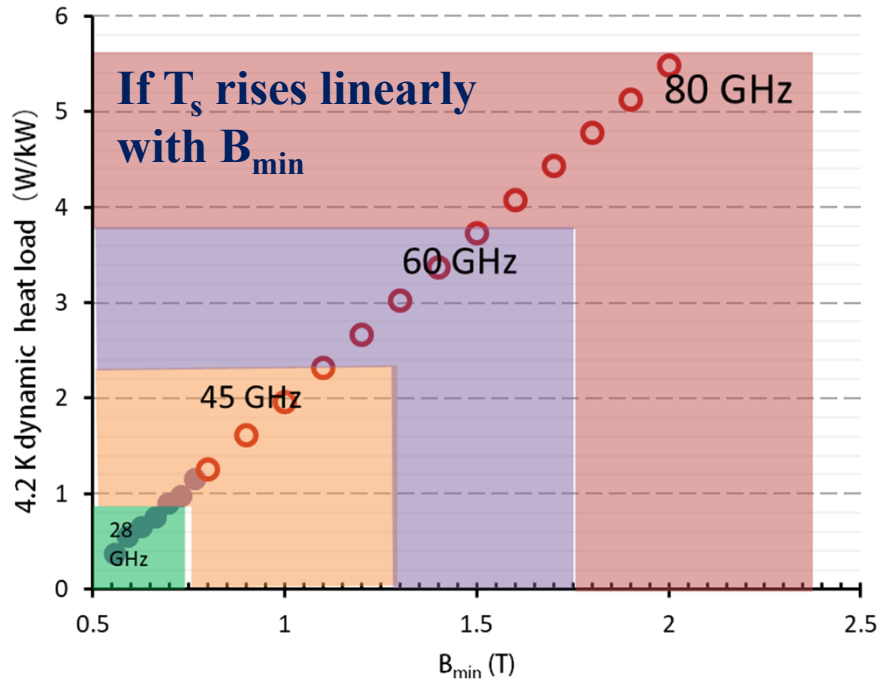


Micro-channel structure of 0.4 mm × 20

Please see Guo's talk 1147 on Tuesday



Status of F ECR Development : Bremsstrahlung



◆ ~ 0.6 W/kW@28 GHz, 1~2 W/kW@45 GHz?

◆ 20 kW@45 GHz $\sim >20$ W@4.2 K?

J. B Li, et al., Plasma Phys. Control. Fusion **62** (2020) 095015
Also see two Li's talks 1122 & 1082 on Tuesday & Wednesday

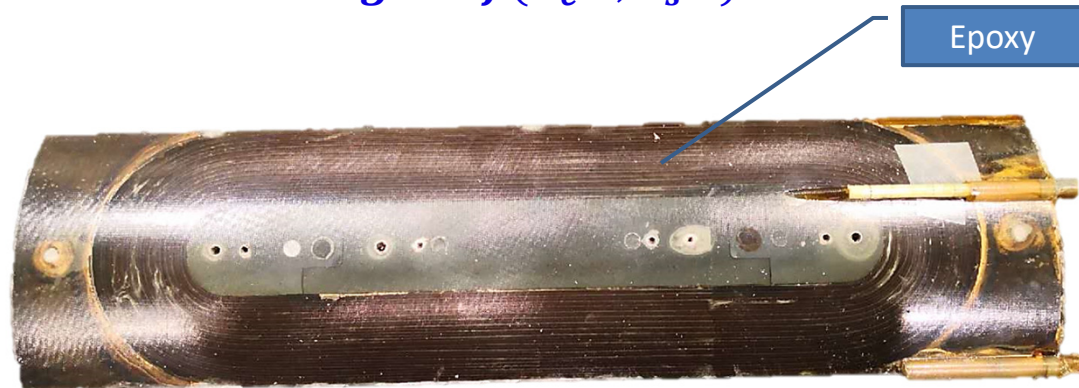


Status of FOCR Development : Insulators



Yellowish PEEK insulator
after high power operation
(1.5 mm Ta shielding)

$$\text{damage} = f(n_e \uparrow, T_s \uparrow)$$

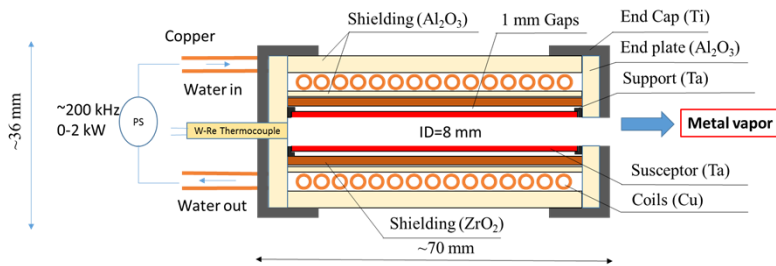


- Main insulator is replaceable
- What if Coil epoxy degrades after long time exposure, which literally needs high quality of insulation property (5 kV standard)

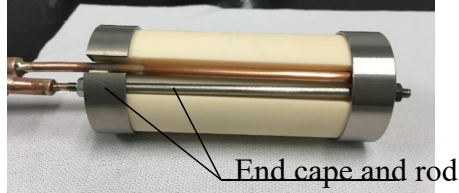


Status of **F**ECR Development : **U**ranium Beam

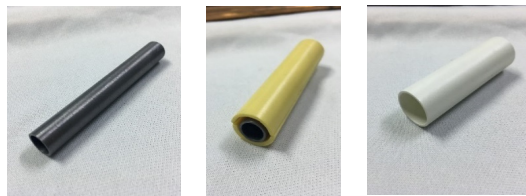
Uranium beam production with HTO



>2000°C Inductive Heating Oven



End cape and rod

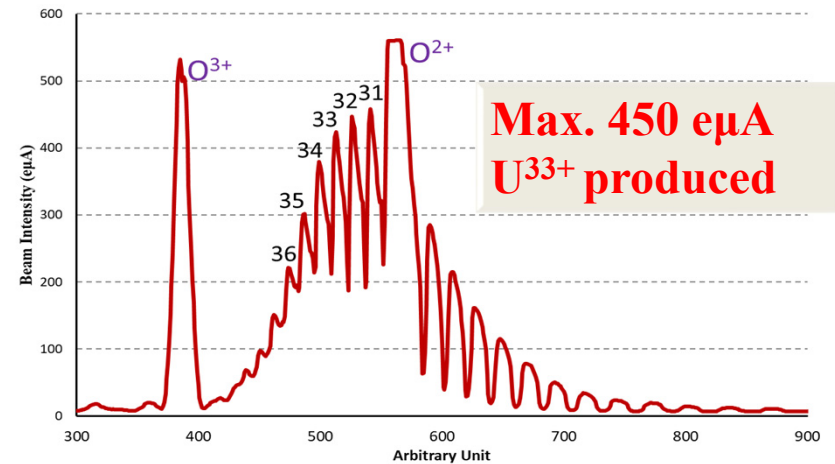
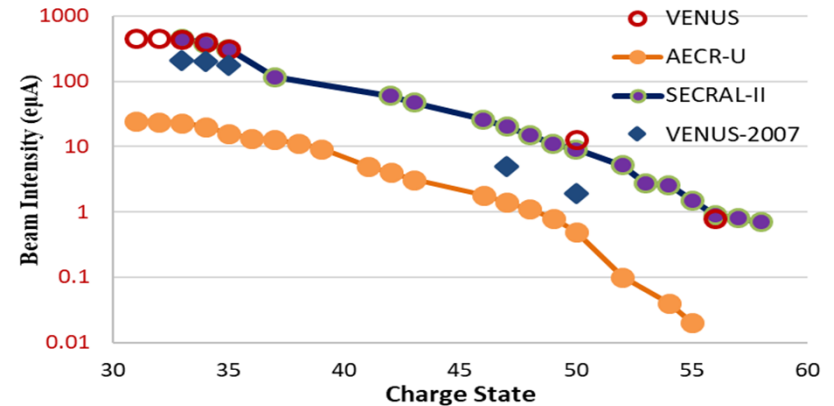


Crucible, Thermal Shield & Insulator



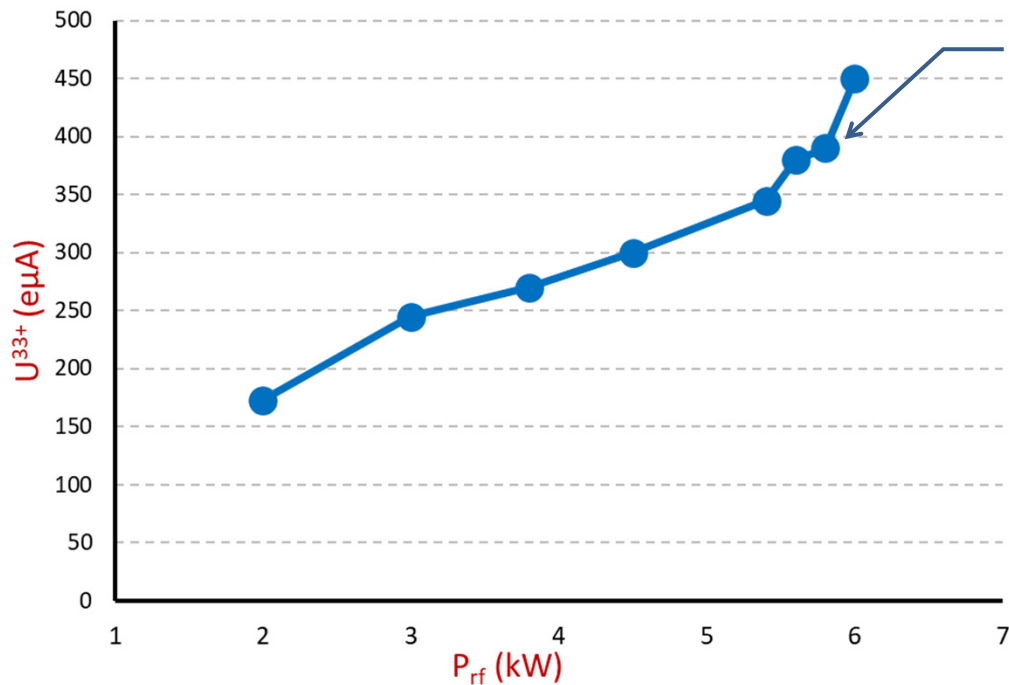
Off-line Test

Wang Lu @ talk 1155, on Tuesday

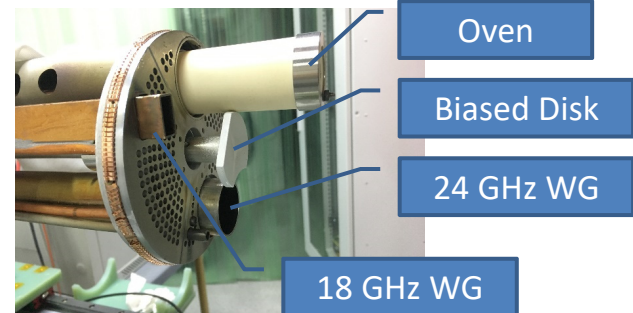




Status of **F**ECR Development : **U**ranium **B**eam

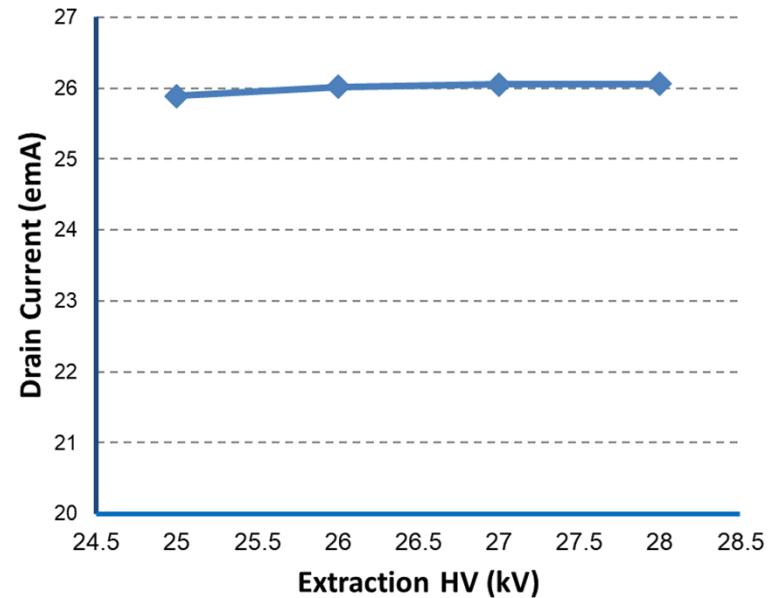
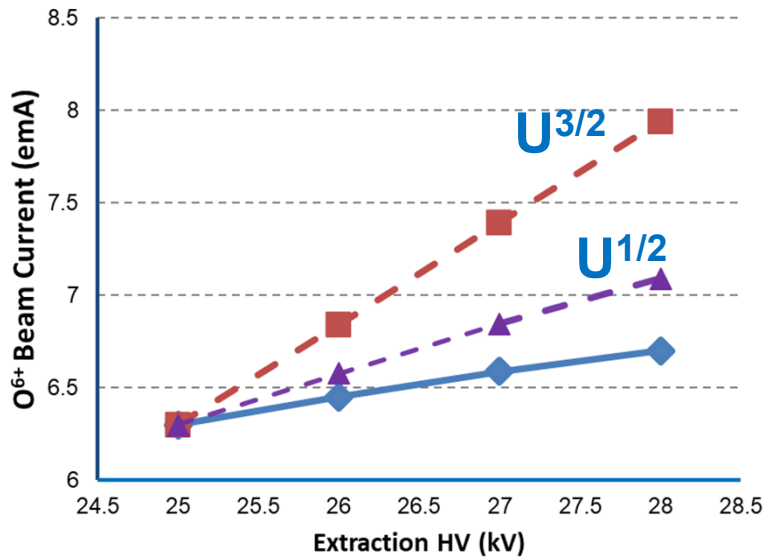


- Plasma heating contribution obvious
- Oven temperature still has margin
- Potentials at 28 GHz, limited by power limit in 2019 (chamber damage at high power)





Status of **F**ECR Development : **Beam Extraction**

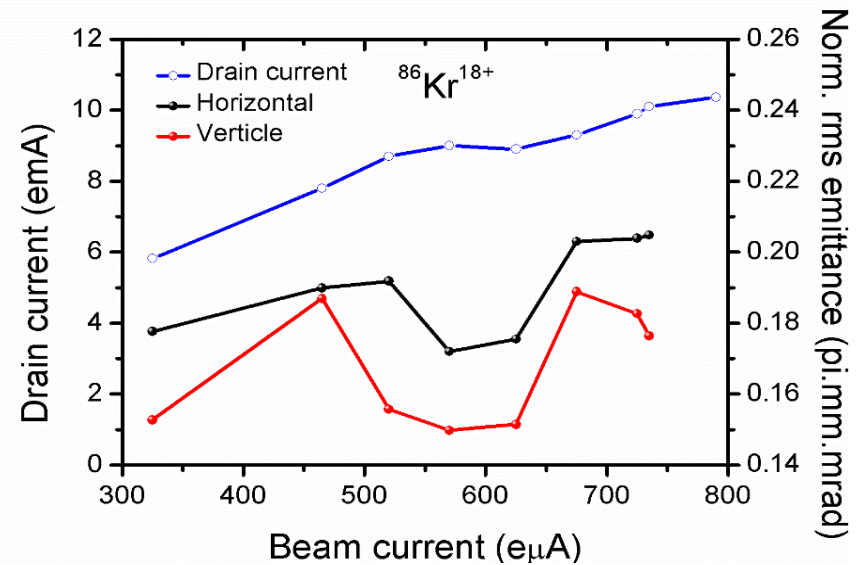
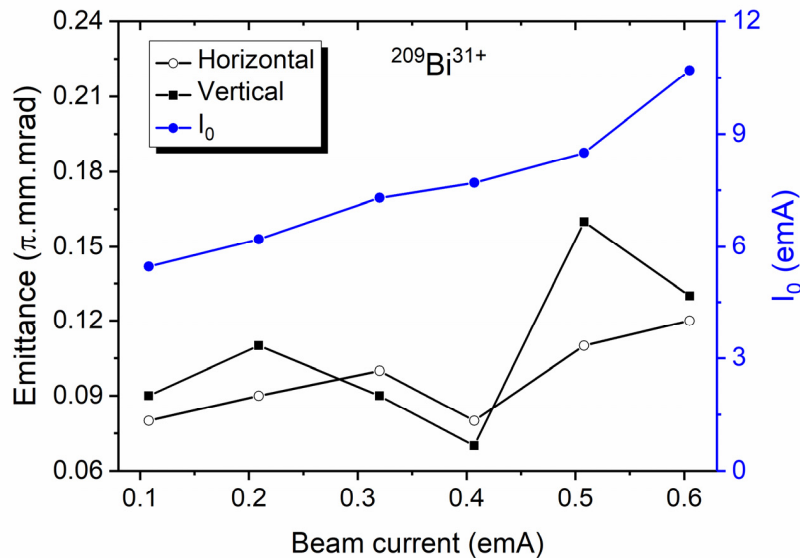


Higher extraction voltage==

- Higher beam transmission efficiency
- Better beam quality in terms of SPC



Status of **F**ECR Development : **B**eam **E**xtraction

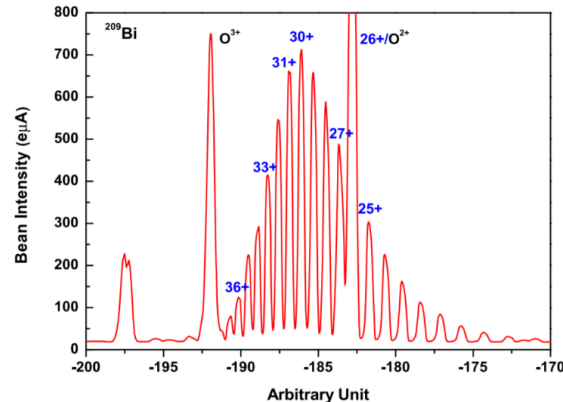
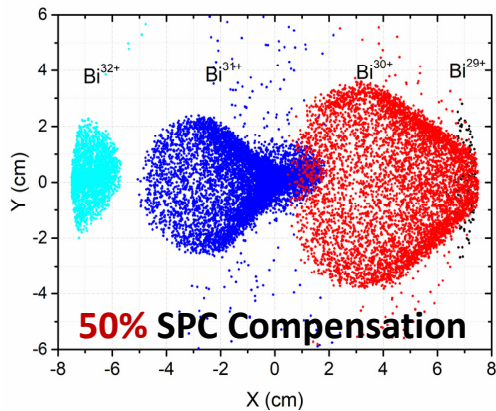
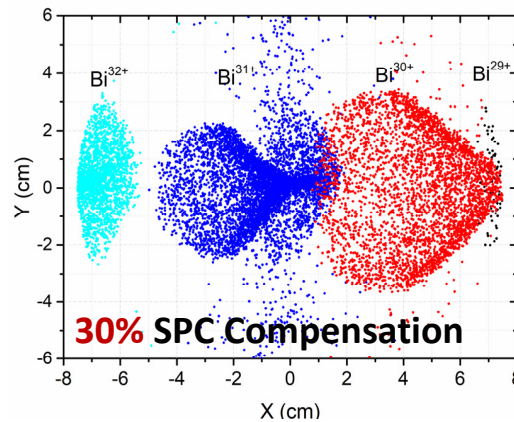
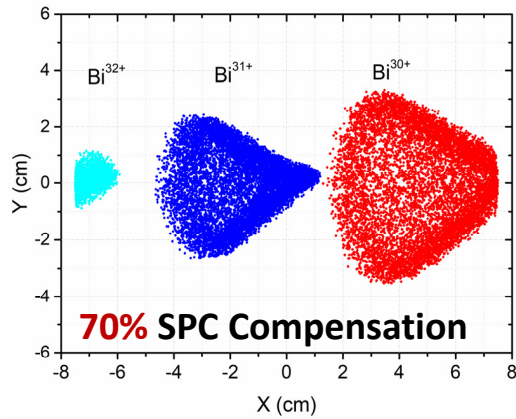


- Beam emittance degradation not proportional to I_q
- Space charge not dominant at extraction and transmission
- Plasma condition and beam extraction critical

Y. Yang, et al., Phys. Rev. Accel. Beams, **22**, 110101 (2019)



Status of **F**ECR Development : **Beam Extraction**

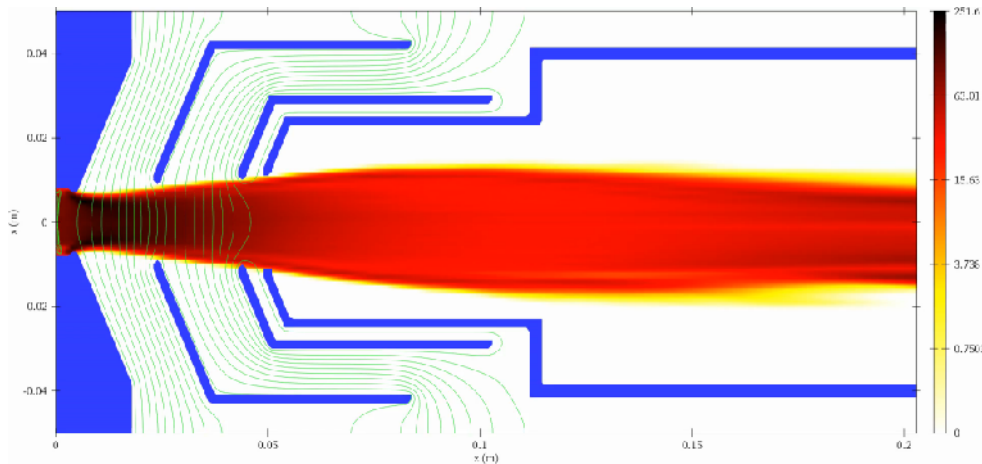


Evidence of SPC not dominant in ion source extraction and transmission

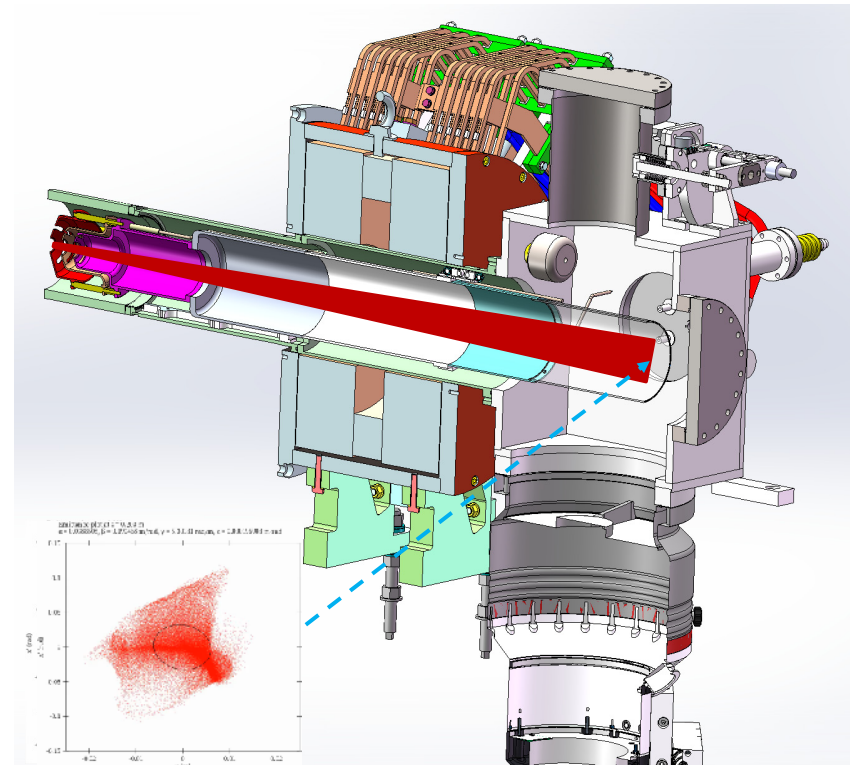
• $I_{\text{total}}=13 \text{ emA}$, $I_{\text{Bi}31+}=0.65 \text{ emA}$.



Status of F ECR Development : Beam Extraction



- ❑ Max. 50 kV extraction voltage
- ❑ 4-electrode extraction system
- ❑ Variable beam extraction optics
- ❑ Dual-solenoid solution before dipole magnet (independent control of beam focusing and matching)



Z. Shen @ talk 1142, on Wednesday



Summary

- ✓ X ◆ Reliable and safe SC-magnet for 45 GHz plasma confinement
- ✓ X ◆ Effective coupling to the plasma of 20 kW/45 GHz microwave power
- ? ◆ 20 kW microwave heated plasma operation reliability and stability:
- ? ◆ Strong bremsstrahlung radiation problems
- ? ◆ Intense high charge state ion beam (20-40 emA) extraction, transport and beam quality control
- ⚙ ◆ Intense metallic beam production, especially of refractory materials: U, W, Ta, Mo, Ti, Ni...



Acknowledgement



Xi'an Superconducting Magnet Technology Inc.

- Coil fabrication
- Cold mass fabrication and assembly



Bruker OST LLC.

- Nb₃Sn Wire



Western Superconducting Tech Co., Ltd.

- Nb₃Sn Wire
- Wire braiding



Lanzhou Kejin Taiji New Technology Co., Ltd.

- Mirror structure
- Mechanical mapping



Shanghai Chenguang Medical Technologies Co., Ltd.

- Cryogenic system fabrication and integration



GyCOM Co., Ltd.

- Gyrotron microwave generator and microwave transmission solutions



Lawrence Berkeley National Laboratory

- Coldmass structure design



RIKEN

- High temperature oven

Fruitful discussions and suggestions:

D. Xie, C. Lyneis, D. Hitz, T. Thuiller, T. Nakagawa

O. Tarvainen, E. Ravaoli, X. J. Liu, W. Kasperek

**Welcome collaborations and
Postdoc research !!**